


FORM PTO-1449		Atty. Docket No.: 55463/101/102	Serial No.: 08/327,979
<p>LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT</p> 		Applicant: Wayne A. Bonin	
		Filing Date	
		Group Art:	
		October 24, 1994	2605

U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Date	Name	Class	Sub Class	Filing Date If Appropriate
DS	AA 3,307,407	03/07/67	Berg et al.	1	1	
	AB 3,314,493	04/18/67	Kennedy	1	1	
	AC 4,040,118	08/02/77	Johnston	1	1	
	AD 4,694,687	09/22/87	Bonin et al.	1	1	
	AE 4,970,374	11/13/90	Ueda et al.	1	1	
	AF 5,092,174	03/03/92	Reidemeister et al.	1	1	
	AG 5,115,291	05/19/92	Stokes	1	1	
↓	AH 5,134,886	08/04/92	Ball	1	1	
DS	AI 5,174,159	12/29/92	Jacobsen et al.	1	1	
	AJ					

FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Class	Sub Class	Translation Yes No
DS	AK 2 189 607 A	10/28/87	United Kingdom	1	1	
	AL					
	AM					

David H.

15 March 1995



OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

✓			Wickramasinghe, "Scanned-Probe Microscopes", <u>Scientific American</u> , October, 1989, pp. 98-105.
	AO	✓	Grigg, et al., "Tip-sample forces in scanning probe microscopy in air and vacuum", <u>J. Vac. Sci. Technol. A</u> , Vol. 10, No. 4, Jul/Aug, 1992, pp. 680-83.
	AP	✓	Heerens, "Application of capacitance techniques in sensor design", <u>J. Phys. E. Sci. Instrum.</u> , Vol. 19, 1986, pp. 897-906.
	AQ	✓	Nishibori et al., "Ultra-Microhardness of Vacuum-Deposited Films in Ultra-Microhardness Tester", <u>Thin Solid Films</u> , Vol. 48, 1978, pp. 325-331.
	AR	✓	Tsukamoto et al., "Mechanical Properties of Thin Films measurements of Ultramicroindentation Hardness Young's Modulus and Internal Stress",
	AS	✓	Yanagisawa et al., "An Ultramicro Indentation Hardness Tester and Its Application to Thin Films", <u>Lubrication Engineering</u> , Vol. 45, January, 1987, pp. 52-56.
	AT	✓	Newey et al., "An ultra-low-load penetration hardness tester", <u>J. Phys. E. Sci. Instrum.</u> , Vol. 15, 1982, pp. 119-122.
	AU	✓	Wierenga et al., "Ultramicroindentation apparatus for the mechanical characterization of thin films", <u>J. Appl. Phys.</u> , Vol. 55, No. 12, June 15, 1984, pp. 4224-47.
	AV	✓	Wierenga et al., "Ultramicrohardness Experiments on Vapour-Deposited Films of Pure Metals and Alloys", <u>Thin Solid Films</u> , Vol. 119, 1984, pp. 375-82.
	AW	✓	Burnham et al., "Measuring the nanomechanical properties and surface forces of materials using an atomic force microscope", <u>J. Vac. Sci. Technol. A</u> , Vol. 7, No. 4, Jul/Aug, 1989, pp. 2906-13.
	AX	✓	Oliver et al., "Thin Film Characterization Using a Mechanical Properties Microprobe", <u>Thin Solid Films</u> , Vol. 153, 1987, pp. 185-96.
	AY	✓	Wu, "Microscratch and load relaxation tests for ultra-thin films", <u>J. Mater. Res.</u> , Vol. C, No. 2, February, 1991, pp. 407-26.
✓	AZ	✓	Holman et al., "Using capacitive sensors for in situ calibration of displacements in a piezo-driven translation stage of an STM", <u>Sensors and Actuators A</u> , Vol. 36, 1993, pp. 37-42.
✓	BB	✓	Weihs et al., "Mechanical deflection of cantilever microbeams: A new technique for testing the mechanical properties of thin films", <u>J. Mater. Res.</u> , Vol. 3, No. 5, Sept/Oct. 1988, pp. 931-942.

EXAMINER: *[Signature]*

DATE CONSIDERED: 15 Mar 1995

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.